

Nanofabrication Central Facility (NCF)

Rate Schedule for INTERNAL Brown Users

Effective July 1, 2020 – June 30, 2021 (Rates Subject to Change)

The purpose of the NCF rate schedule is to offset the annual cost of operating the facility by collecting a fee based upon usage. The NCF is a self-use facility with trained personnel who will provide new users with a facility orientation and instrument tutorial. Internal Brown users must have a valid Brown University ID and academic appointment and must provide a default account number from the Brown University Workday System. If a user's default account is set to charge F&A, then it will be applied to the following internal rates. Usage of each facility is based upon a user agreement and compliance to the terms stated within that agreement.

Effective July 2018, the Brown internal user rate for all IMNI facilities will be extended to Brown University Hospital Affiliates and Rhode Island Academic Institutions. The following rate are direct cost dollars.

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The usage calculation is based on a per use method for all major and supportive instruments. The clean room usage is charged per day, with a clean room exemption (no clean room charge) when used in conjunction with a major instrument during the same visit.			
Description	Research Use	Instructional Course Use	Unit
Clean Room Only: This includes the use of chemicals, spinner, hot plate, and hood (without the use of any major or supportive instruments).	\$ 49.00	\$ 49.00	per day
Major Instruments: The use of major instruments also includes the necessary chemical treatments.			
Heidelberg MLA150 Maskless Aligner	\$99.00	\$99.00	per use
Karl Suss MJB3 UV300 Mask Aligner	\$99.00	\$99.00	per use
NIL Technology Nano Imprinter	\$99.00	\$99.00	per use
Newport-Oriel Flexible Mylar-Mask Lithography System	\$99.00	\$99.00	per use
Cambridge NanoTech Fiji F200 Atomic Layer Deposition System	\$99.00	\$99.00	per use
Electron Beam Evaporator	\$99.00	\$99.00	per use
Lesker Lab-18	\$99.00	\$99.00	per use
Angstrom Multi-Target Sputtering System	\$99.00	\$99.00	per use
Angstrom Organic Evaporator	\$99.00	\$99.00	per use
PlasmaTherm Model 790 RIE/PECVD System	\$99.00	\$99.00	per use
SPTS LPX Inductively Coupled Plasma RIE System	\$99.00	\$99.00	per use
Supportive Instruments:			
RTA Rapid Thermal Annealer	\$26.00	\$26.00	per use
Wet & Dry Oxidation Furnace	\$26.00	\$26.00	per use
Annealing & Drive-in Heat Treatment	\$26.00	\$26.00	per use
Dektak3 - Profilometer	\$26.00	\$26.00	per use
JA Woollam M-2000 Ellipsometer	\$26.00	\$26.00	per use
Instrument Assisted Use by Brown Facility Technical Staff: Prior approval required. This is a self-use facility unless otherwise requested as part of the user agreement. Charge is in addition to the instrument time.	\$59.00*	\$59.00*	per hour
		*Plus Instrument Time	

Key for Processes	
	Lithography
	Thin Film Deposition
	Plasma Etching
	Furnaces
	Characterization